Aberration-Corrected TEM Application Form

1. Personal Information:

Name		Staff/Student ID	
Telephone		E-mail	
University		Department	
Post		MCPF Account	

2. Sample Information:

a. Sample Number:

b. Chemical Formula:

c. Physical Status (e.g. powder, thin film, etc.):

d. Dimensions (e.g. diameter, thickness, etc.):

e. Stability under electron irradiation and vacuum:

f. Area of Interest (please indicate by attaching low-magnification TEM pictures):

g. Pre-characterization (please indicate the machine model you used and attach high-resolution TEM images if applicable):
- Machine Model:
- High-resolution TEM Images:

3. Characterization Details:

Functionality	Please describe your experimental requirements and objectives
STEM Imaging (200kV, 80kV, 60kV and 30kV)	
EDX	
EELS	
Tomography	
Other	

4. Information for Charging:

a. Source of Funding (please tick as appropriate):

- ☐ RGC/UGC, ITF and Instructional Use of HKUST
- ☐ Non-RGC/UGC/ITF of HKUST and RGC/UGC/ITF of other Institutions
- ☐ Industrial and Consulting Work of HKUST and other Institutions
- ☐ Other (please indicate the details): _____.

b. Account/Project No.:

c. Principle Investigator:

d. Project Name:

e. Completion Date:

5. Acknowledgement:

Please acknowledge the support of the aberration-corrected TEM characterization facility and the CRF project at MCPF of HKUST in your publications or presentations.

Example: **"The TEM characterization of this research work was carried out on JEOL JEM-ARM200F aberration-corrected TEM (project no. C6021-14E) in the Materials Characterization and Preparation Facility, the Hong Kong University of Science and Technology."**

6. Approval of Supervisor:

Please note that by signing this form, you agree that your research staff/student has your approval to apply for AC-TEM sessions and that he/she will comply with MCPF regulations regarding the use of this AC-TEM.

Name		Position	
University		Department	
Telephone		E-mail	

Signature: _____ Date: _____.